

ABSTRACT

DEFECT DETECTION DEVICE AND DEFECT DETECTION METHOD

5 A defect detection device (100) that detects defects in a semiconductor device (13) comprises
ultrasonic speakers (21) that ultrasonically vibrate the semiconductor device (13), a laser source
(30) that irradiates the semiconductor device (13) with collimated laser light (32), a camera (40)
that has an imaging element (42) which acquires images by imaging the semiconductor device
(13) that has been irradiated with the collimated laser light (32), and a detection unit (55) that
10 detects defects in the semiconductor device (13) on the basis of the images picked up by the camera
(40), wherein the detection unit (55) detects defects in the semiconductor device (13) on the basis
of the deviation between images acquired by the camera (40) of the semiconductor device (13)
when static and when ultrasonically vibrated.

15 Figure 1